

Study of PPDs with multi-wavelength laser microscope system

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Measurement of PPD (Pixelated Photon Detector) characteristics with various wavelengths is important for understanding and improvement of the sensor performances. We have developed a new pulsed laser microscope system whose wavelength is continuously tunable from 410 nm to 2200 nm by using OPO laser system. Laser spot can be focused to ~ 2 μm , small enough to measure pixel-by-pixel performance of PPD. In this workshop, new multi-wavelength measurements of various types of PPDs using the laser microscope system will be reported.

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